



*Signature*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**  
(Case No. 213.002-D1-US)

In the Application of: <b>Ye et al.</b>	)	Group Art Unit: <b>2878</b>
	)	
Serial No: <b>10/646,313</b>	)	Before Examiner: <b>Que Tan Le</b>
	)	
Filed: <b>August 22, 2003</b>	)	
	)	
Title: <b>System and Method for Lithography</b>	)	
<b>Process Monitoring and Control</b>	)	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**Certificate of Mailing under 37 CFR 1.8**

I hereby certify that the attached Statement of Related Applications (1 page) is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

on May 17, 2004.

*Michiko Sites*  
Signature

*Michiko Sites*  
Print Name of Person Signing Certificate



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**STATEMENT OF RELATED APPLICATIONS**

Dear Sir:

The above-referenced application is related to the following applications which all claim priority to "System and Method for Lithography Process Monitoring and Control", Serial No. 10/390,806, filed March 18, 2003:

1. "System and Method for Lithography Process Monitoring and Control", Serial No. 10/703,732, filed November 7, 2003 (still pending); and
2. "System and Method for Lithography Process Monitoring and Control", Serial No. 10/755,809, filed January 12, 2004 (still pending).

Date: May 17, 2004

Respectfully submitted,

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650-968-8079